

**WASTE TREATMENT AND IMMOBILIZATION PLANT
CHAPTER 4G
DIRECT-FEED LOW-ACTIVITY WASTE (EFFLUENT MANAGEMENT FACILITY)
CHANGE CONTROL LOG**

Change Control Logs ensure that changes to this unit are performed in a methodical, controlled, coordinated, and transparent manner. Each unit addendum will have its own change control log with a modification history table. The “**Modification Number**” represents Ecology’s method for tracking the different versions of the permit. This log will serve as an up to date record of modifications and version history of the unit.

Modification History Table

Modification Date	Modification Number
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CHAPTER 4G
DIRECT FEED LOW-ACTIVITY WASTE (EFFLUENT MANAGEMENT FACILITY)

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2 **CHAPTER 4G**
3 **DIRECT FEED LOW-ACTIVITY WASTE (EFFLUENT MANAGEMENT FACILITY)**
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4G.0 DIRECT FEED LOW-ACTIVITY WASTE (EFFLUENT MANAGEMENT FACILITY)

1 The Direct Feed Low-Activity Waste (DFLAW) configuration allows for the operation of the LAW
 2 Vitrification Facility and Analytical Laboratory (Lab) prior to operation of the Pretreatment Facility. In
 3 this configuration, low-activity waste is fed directly from the Hanford Tank Farms LAW Pretreatment
 4 System (LAWPS) to the LAW Vitrification Facility. The LAWPS is permitted as a separate Treatment,
 5 Storage, and Disposal Facility under the Hanford Dangerous Waste Permit. The DFLAW configuration
 6 differs from the baseline configuration. In the baseline configuration, low-activity waste and high-
 7 activity waste is transferred directly from the Hanford Tank Farms to the Pretreatment Facility and treated
 8 by ultrafiltration and cesium ion exchange before transfer to the LAW Vitrification Facility or High-Level
 9 Waste (HLW) Vitrification Facility; in addition, the generated off-gas effluents from the LAW
 10 Vitrification Facility and HLW Vitrification Facility processes are returned to the Pretreatment Facility.
 11 In the DFLAW configuration, low-activity waste bypasses the Pretreatment Facility and feeds directly
 12 into the LAW Vitrification Facility. As such, the replication of some functions of the Pretreatment
 13 Facility is required. The Effluent Management Facility (EMF) is in place to replicate activities conducted
 14 in the baseline configuration, including the management and treatment of the liquid effluent from the
 15 LAW Vitrification Facility Radioactive Liquid Waste Disposal (RLD) System and the Lab RLD System,
 16 and management of the effluent from the LAW Secondary Offgas/Vessel Vent Process (LVP) System.
 17 Waste received at the LAW Vitrification Facility from the LAWPS will not be characterized as ignitable
 18 (D001) or reactive (D003); therefore, tanks/vessels associated with the DFLAW configuration are not
 19 required to be designed to manage reactive or ignitable wastes.

20 Permitted processes involved with the DFLAW configuration include the Direct Feed LAW EMF Process
 21 (DEP) System, the Direct Feed LAW EMF Vessel Vent Process (DVP) System, and the underground
 22 waste transfer lines.

23 Direct Feed LAW EMF Process (DEP) System

24 The DEP System allows the EMF to collect, process, recycle, and dispose of the liquid effluent from the
 25 Lab, LAW Vitrification Facility, and underground waste transfer line flushes. The DEP System
 26 performs the following functions:

- 27 • Receipt of liquid effluent.
- 28 • Liquid effluent volume reduction.
- 29 • Process stream sampling.
- 30 • Waste conditioning.

31 The DEP System includes the following major components:

- 32 • An evaporator system consisting of an evaporator separator vessel (DEP-EVAP-00001),
 33 evaporator reboiler (DEP-RBLR-00001), evaporator condensers (DEP-COND-0001/2/3),
 34 recirculation pump, and vacuum ejectors.
- 35 • Low-Point Drain Vessel (DEP-VSL-00001).
- 36 • Evaporator Feed Vessel (DEP-VSL-00002).
- 37 • Evaporator Concentrate Vessels (DEP-VSL-00003A/B/C).
- 38 • Overhead Sampling Vessels (DEP-VSL-00004A/B).
- 39 • Process Condensate Lag Storage Vessels (DEP-VSL-00005A/B).
- 40 • Other equipment, including pumps, filters, and associated piping and valves.

41 The DEP System evaporator loop functions to reduce the volume of liquid effluent that is received from
 42 the LAW Vitrification Facility, Lab and underground waste transfer line flushes, and recycle the
 43 concentrate back to the LAW Vitrification Facility. The design also supports the transfer of the

1 concentrate to the Hanford Tank Farms and to the tanker truck load out area. Condensate from the DEP
2 System process can be disposed of at the Liquid Effluent Retention Facility (LERF)/ Effluent Treatment
3 Facility (ETF).

4 The evaporator loop consists of the evaporator separator vessel, reboiler, condensers, and the recirculation
5 piping. As the liquid effluent circulates through the reboiler, the temperature rises. Then, the liquid rises
6 into the separator vessel, the hydrostatic head diminishes, and flash evaporation occurs near the liquid
7 surface. The liquid stream recirculates in the closed loop while the vapor stream enters the evaporator
8 overheads. The evaporator loop operates under a vacuum to reduce the boiling temperatures and
9 minimize corrosion.

10 The reboiler is a tube-and-shell heat exchanger. High pressure steam, supplied from the Balance of
11 Facilities (BOF), is used to heat a secondary steam loop that feeds the heat exchanger shell side, while the
12 evaporator feed circulates through the heat exchanger tubes.

13 Direct Feed LAW EMF Vessel Vent Process (DVP) System

14 The DVP System is comprised of two main parts, air inlet, and exhaust. The DVP System provides
15 vessel ventilation for the DEP System vessels, the purpose of the DVP System is to direct vessel vent
16 gases to emission control systems, and purge hydrogen to maintain the vessel hydrogen concentration
17 below dangerous levels.

18 The DVP System includes the following major components:

- 19 • Process Ventilation Preheaters (DVP-HTR-00001A/B).
- 20 • Process Ventilation Primary HEPA Filters (DVP-HEPA-00003A/B).
- 21 • Process Ventilation Secondary HEPA Filters (DVP-HEPA-00004A/B).
- 22 • Process Ventilation Exhausters (DVP-EXHR-00001A/B).

23 For the DEP System vessels in the LAW Effluent Process Building, a purge air inbleed is used to meet
24 the very low required flow rates. The vessel vent is the exhaust portion of the DVP System and provides
25 suction pressure on the vessel headspace, to draw in the purge air, and mitigate hydrogen accumulation.
26 The discharged air is sent through a preheater, two-stage HEPA filters, and through an exhaust fan to
27 discharge out of the EMF stack. The DVP exhaust fans control and maintain the suction pressure inside
28 the various process vessels, maintaining the continuous purge air inbleed.

29 Underground Waste Transfer Lines

30 The underground waste transfer lines installed to support the DFLAW configuration are coaxial lines that
31 are constructed of stainless steel primary pipe, with a carbon steel encasement pipe that is coated with
32 fusion bonded epoxy (FBE). The coating system and water barrier consist of the FBE, polyurethane
33 insulation, and a jacket or thermoplastic outer water barrier made of high density polyethylene (HDPE).
34 Cathodic protection is not needed for the underground waste transfer lines installed to support the
35 DFLAW configuration as the pipe system is made of corrosion resistant materials, providing water
36 resistant construction to isolate the underground waste transfer lines from the soil and moisture.

37 The underground waste transfer lines transfer waste from various areas to support the DFLAW
38 configuration. Underground waste transfer lines support the receipt of the low-activity waste from
39 LAWPS to the LAW Vitrification Facility, as well as effluent transfers from LAW Vitrification Facility
40 and Lab, to the EMF and the LERF/ETF. Evaporator concentrate is sent back to the LAW Vitrification
41 Facility through the LAWPS underground waste transfer line. In addition, liquid effluent can be
42 transferred from the DEP System to the Hanford Tank Farms.

43 After every waste transfer from the LAWPS to LAW Vitrification Facility, the underground waste
44 transfer lines are flushed and drained to the EMF low-point drain vessel (DEP-VSL-00001); the effluent

1 is collected and processed at the EMF. The effluent is monitored for flow and density to minimize the
2 volume of flush liquid that is transferred to the LAW concentrate receipt vessel.

3 There are eight major WTP underground waste transfer lines that support the EMF process. Line
4 DEP-PB-00009-S32B-03 transfers LAWPS feed from the WTP property boundary to the low-point drain
5 vessel. Line LCP-PB-03368-S32B-03 transfers LAWPS feed and EMF concentrate from the low-point
6 drain vessel to the LAW Vitrification Facility. LAW LVP process effluent and LAW RLD process
7 effluent are transferred from the LAW Vitrification Facility to the EMF through line LVP-ZY-00171-
8 W31A-03. Lab RLD process effluent is transferred from the Lab to the EMF through line RLD-WU-
9 22142-S32B-03. Line DEP-ZS-00069-W31A-03 returns EMF concentrate from the EMF to the WTP
10 property boundary, with transfer to the Hanford Tank Farms. EMF effluent is transferred to the existing
11 LERF/ETF transfer line that connects in between the Pretreatment Facility and the WTP property
12 boundary through lines RLD-ZS-66989-W31A-04 and RLD-ZS-66991-W31A-03.

13 EMF Buildings

14 The EMF, located north of the Lab, is comprised of four buildings, the LAW effluent process building,
15 the LAW effluent drain tank building, the LAW effluent electrical building, and the LAW effluent utility
16 building. The EMF contains an evaporator system, nine major process vessels, three supporting reagent
17 product storage tanks, heating, ventilation and air conditioning (HVAC) equipment, and electrical
18 utilities. The buildings are described in more detail below.

19 Building 25 – LAW Effluent Process Building

20 The LAW effluent process building houses the DEP System and DVP System. The DEP System is the
21 main process system for the EMF and consists of vessels and ancillary equipment used to support the
22 collection, processing, and disposal of the mixed waste effluent from the LAW and Lab Facilities; a more
23 detailed discussion of the processes contained in this building are located in section 4G.2 and 4G.3. The
24 DVP System provides vessel ventilation for the DEP System vessels. A more detailed discussion of this
25 system can be found in 4G.5.

26 Building 25A – LAW Effluent Drain Tank Building

27 The LAW effluent drain tank building consists of the low-point drain vessel (DEP-VSL-00001) and the
28 drain tank maintenance area. The low-point drain vessel is sized to handle flushing of the DFLAW
29 underground waste transfer lines, between the LAWPS and the LAW Vitrification Facility and the
30 effluent lines between the LAW Vitrification Facility, the Lab and the EMF. A more detailed discussion
31 of the processes contained in this building are located in 4G.2.

32 Building 26 – LAW Effluent Utility Building

33 The LAW effluent utility building contains the building ventilation HVAC high efficiency particulate air
34 (HEPA) filters and fans, and the BOF utility pumps and storage vessels. The LAW effluent utility
35 building shares a ventilation system with the LAW effluent process building. The treated DVP offgas
36 from the LAW effluent process building ties into the exhaust duct in the LAW effluent utility building
37 and is discharged to the atmosphere through the 150-foot-high stack. A more detailed discussion of this
38 process can be found in Section 4G.5.1. The building does not contain equipment that manages
39 dangerous or mixed waste.

40 Building 27 – LAW Effluent Electrical Building

41 The LAW effluent electrical building houses most of the EMF electrical equipment, which includes
42 electrical batteries and control/instrumentation equipment. It has a separate power supply and exhaust
43 system. The building does not contain equipment that manages dangerous or mixed waste.

44 [Figure 4G-1](#), EMF Process Flow, presents a simplified process flow diagram of the EMF Process.

4G.1 CONTAINERS

1 The dangerous and mixed waste generated at the EMF is managed in 90-day accumulation areas and
2 satellite accumulation areas pursuant to the requirements in [WAC 173-303-200](#), generating dangerous
3 waste on-site. All waste anticipated to be dangerous or mixed waste is managed in accordance with
4 [WAC 173-303-170](#), requirements for generators of dangerous waste, through [WAC 173-303-230](#), special
5 conditions. The dangerous and mixed waste is labeled and characterized in accordance with requirements
6 in [WAC 173-303-070](#), designation of dangerous waste. Information on all 90-day accumulation areas and
7 satellite accumulation areas is maintained as required in the Hanford Dangerous Waste Permit, Part II
8 General Facility Conditions, permit condition II.I.1.a.

9 The dangerous and mixed waste generated at the EMF is containerized secondary waste. The following
10 are examples of the generated secondary waste:

- 11 • Spent or failed equipment
- 12 • Offgas HEPA filters
- 13 • Personal Protective Equipment
- 14 • Spent maintenance materials

4G.2 TANK SYSTEMS

15 Permitted tank systems are designed to comply with bounding design criteria, such as pH, temperature,
16 and pressure conditions. The EMF evaporator feed vessel (DEP-VSL-00002), the overhead sampling
17 vessels (DEP-VSL-00004A/B), evaporator concentrate vessels (DEP-VSL-00003A/B/C), and the process
18 condensate lag storage vessels (DEP-VSL-00005A/B) are located outside in secondary containment areas.
19 The remaining EMF process vessel, the low-point drain vessel (DEP-VSL-00001), is located indoors, in a
20 below grade process area. All tank systems are located within process areas with controlled access.

21 In general, overflows are prevented by inventory controls in conjunction with level monitoring. The fluid
22 level in a vessel is maintained within low- and high-level ranges. Appropriate alarm settings are used to
23 note deviations from the designed settings. Automatic and operator alarm responses are designed to shut
24 down feed to the vessel when the high-level settings are exceeded.

25 A list of all EMF tank systems can be found in [Table 4G-1](#), Effluent Management Facility Tank Systems.

4G.2.1 Low-Point Drain Vessel (DEP-VSL-00001)

26 The low-point drain vessel (DEP-VSL-00001) is located below grade, within an enclosed room (ED-
27 B001), in the LAW effluent drain tank building. The low-point drain vessel collects effluent from
28 underground waste transfer line flushes, including effluent from flushes of the underground waste transfer
29 lines.

30 The low-point drain vessel also collect effluent from the DEP System concentrate transfer line relief
31 valve; west process area sumps (DEP-SUMP-00002A/B), feed vessel area sumps (DEP-SUMP-
32 00004A/B), tanker truck loadout sump (DEP-SUMP-00008); and the drains from the evaporator
33 concentrate/feed vessels LAW effluent cooler (DEP-HX-00001). In addition, the low-point drain vessel
34 collects overflow from several DEP System process vessels, including the evaporator feed vessel (DEP-
35 VSL-00002), evaporator concentrate vessels (DEP-VSL-00003A/B/C), overhead sampling vessels (DEP-
36 VSL-00004A/B), and process condensate lag storage vessels (DEP-VSL-00005A/B), as well as effluent
37 from the sampler return line, evaporator drain line, fume hood drain line, and off-specification evaporator
38 concentrate drain line.

39 The vessel drain line, overflow pipe, and the low-point drain sump (DEP-SUMP-00001) are
40 decontaminated with demineralized water. The demineralized water used for decontamination is
41 ultimately sent to LERF/ETF.

1 The low-point drain vessel is equipped with a vessel agitator (DEP-AGT-00001) to help prevent buildup of
2 settled solids in the waste. The agitator has a manual start and operates when transferring or sampling
3 liquid. The low-point drain vessel is vented to the vessel vent header and overflows to the low-point drain
4 area sump through a loop seal. This sump effluent is transferred to the evaporator feed prefilter
5 (DEP-FILT-00003) and then to the evaporator feed vessel by the low-point drain vessel area sump pump.
6 In-vessel pumps (DEP-PMP-00001A/B) are used to transfer the low-point drain vessel contents to the
7 evaporator feed vessel through the evaporator feed prefilter. The evaporator feed prefilter is used to keep
8 any solids larger than 5 microns from entering the evaporator process.

4G.2.2 Evaporator Feed Vessel (DEP-VSL-00002)

9 The evaporator feed vessel (DEP-VSL-00002) receives filtered effluent from multiple sources and caustic
10 solution from the caustic tank (SHR-TK-00013) for pH adjustment.

11 Effluent from the LAW plant wash vessel (RLD-VSL-00003), the RLD submerged bed scrubber
12 condensate collection vessel (RLD-VSL-00005), the Lab RLD vessel (RLD-VSL-00164), and the low-
13 point drain vessel (DEP-VSL-00001) are collected in the evaporator feed vessel prior to transfer to the
14 evaporator separator vessel (DEP-EVAP-00001).

15 The evaporator feed vessel also receives off-specification effluent from the overhead sampling vessels
16 (DEP-VSL-00004A/B), off-specification concentrate from the evaporator separator vessel (DEP-EVAP-
17 00001), and sump effluent from the low-point drain sump (DEP-SUMP-00001).

18 The evaporator system concentrates the feed from the evaporator feed vessel to reduce the overall effluent
19 volume for recycle to the LAW Vitrification Facility, or for transfer to the Hanford Tank Farms and the
20 tanker truck load out area. In addition, the evaporator system provides an overhead condensate that can be
21 processed by LERF/ETF.

22 The evaporator feed vessel is equipped with eductors to mix vessel contents to support sampling. The
23 eductors circulate fluid from the evaporator feed vessel using recirculation pumps and operate while the
24 pumps are running. In the event of an off-normal condition within the EMF, the evaporator feed vessel
25 recirculation pumps can bypass the evaporator separator vessel and transfer effluent to the Hanford Tank
26 Farms after passing through the evaporator concentrate/feed vessels LAW effluent cooler
27 (DEP-HX-00001).

4G.2.3 Evaporator Concentrate Vessels (DEP-VSL-00003A/B/C)

28 The evaporator concentrate vessels (DEP-VSL-00003A/B/C) are used to accumulate concentrated
29 effluent from the evaporator separator vessel (DEP-EVAP-00001). In addition, the evaporator
30 concentrate vessels may receive filter backflush from the evaporator feed prefilter (DEP-FILT-00003) and
31 caustic solution from the caustic tank (SHR-TK-00013). The concentrate effluent can either be recycled
32 back to the LAW LCP vessels (LCP-VSL-00001/2), to the Hanford Tank Farms, or to the tanker truck
33 load out area. In the event of an overflow, the liquid flows by gravity into the low-point drain vessel
34 (DEP-VSL-00001). Each batch is sampled in the evaporator concentrate vessels and characterized before
35 it is sent to the LAW Vitrification Facility or the Hanford Tank Farms.

36 The evaporator concentrate transfer pumps (DEP-PMP-00003A/B) are used to circulate fluid from the
37 evaporator concentrate vessels via eductors. The evaporator concentrate pumps also transfer the
38 evaporator concentrate vessels' contents to LAW LCP vessels, the Hanford Tank Farms, or the tanker
39 truck load out area.

40 When transferring concentrate to the Hanford Tank Farms, the effluent stream must comply with the
41 Hanford Tank Farm waste acceptance criteria. The evaporator concentrate transfer pumps transfer the
42 effluent through the evaporator feed prefilter (DEP-FILT-00003) to remove solids, the filtered effluent is
43 mixed with process condensate and sodium nitrite, as necessary, and then the effluent is sent through the

1 evaporator concentrate/feed vessel LAW effluent cooler (DEP-HX-00001) before being sent to the
2 Hanford Tank Farms.

4G.2.4 Overhead Sampling Vessels (DEP-VSL-00004A/B)

3 The overhead sampling vessels (DEP-VSL-00004A/B) receive inter and after condenser condensate from
4 the evaporator primary condenser (DEP-COND-00001), inter-condenser (DEP-COND-00002) and the
5 after-condenser (DEP-COND-00003), caustic scrubber fluids from the LVP system (LVP-TK-00001), off-
6 specification condensate from the process condensate lag storage vessels (DEP-VSL-00005A/B), effluent
7 from west process area sumps (DEP-SUMP-00002A/B), effluent from the feed vessel area sumps
8 (DEP-SUMP-00004A/B) and liquid from the non-radioactive liquid waste disposal system (NLD) sumps
9 (NLD-SUMP-00031/32). Only qualified effluent is transferred to the overhead sampling vessels. Effluent
10 in the west process area sumps and the feed vessel area sumps is also characterized using sampling or
11 process knowledge prior to transfer to the overhead sampling vessels. Each process batch is sampled in
12 the concentrate vessels and characterized before it is sent to the LAW facility or to the Hanford tank farms.
13 Similarly, each batch is sampled in the overhead sampling vessels and characterized before it is sent to the
14 process condensate lag storage vessels. If the waste does not meet LERF/ETF requirements (i.e., off-
15 specification), it can be blended in the other overhead sampling vessel in attempt to meet the LERF/ETF
16 requirements. If required, the liquid effluent can be transferred to the evaporator feed vessel (DEP-VSL-
17 00002).

18 The overhead sampling vessel transfer/recirculation pumps (DEP-PMP-00004A/B/C) are used to
19 recirculate the overhead sampling vessels contents to a sample connection, where samples are collected
20 and fluid is returned to the overhead sampling vessels through the eductors. After the content quality has
21 been verified through laboratory testing, pumps are used to transfer the contents to the process condensate
22 lag storage vessels. In the event of an overflow, the liquid gravity drains to the low-point drain vessel
23 (DEP-VSL-00001).

4G.2.5 Process Condensate Lag Storage Vessels (DEP-VSL-00005A/B)

24 The process condensate lag storage vessels (DEP-VSL-00005A/B) receive batches of process condensate
25 from the overhead sampling vessels (DEP-VSL-00004A/B), secondary steam blowdown (SCW-VSL-
26 00054) and effluent from the east process area sumps (DEP-SUMP-00003A/B) and the process
27 condensate vessel area sumps (DEP-SUMP-00005A/B). The vessels allow for lag storage before sending
28 the process condensate to the LERF/ETF. In the event of an overflow, the liquid will flow by gravity into
29 the low-point drain vessel (DEP-VSL-00001). While sampling normally occurs in the overhead sampling
30 vessels, the process condensate vessel can also be sampled prior to transfer to LERF/ETF.

31 Recirculation pumps are used to circulate fluid in the process condensate lag storage via eductors. The
32 recirculation pumps are also used to flush the evaporator feed prefilter (DEP-FILT-00003), flush the low-
33 point drain vessel transfer pumps, flush the pump suction lines of the three evaporator concentrate
34 vessels, as well as dilute evaporator concentrate prior to transfer back to the Hanford Tank Farms. The
35 condensate is added to the evaporator concentrate in a tee prior to the evaporator concentrate/feed vessel
36 LAW effluent cooler (DEP-HX-00001). The flow ratios, based upon sampling before the transfer, are
37 recorded and a sample is taken for post transfer confirmation to verify that the transfer meets the Hanford
38 Tank Farms waste acceptance criteria. The effluent is then transferred to the Hanford Tank Farms.

4G.3 MISCELLANEOUS UNITS

39 The following miscellaneous units are part of the DEP System and are managed under this permit as tanks
40 and tank systems. [Table 4G-2](#) Effluent Management Facility Miscellaneous Units (Systems and Sub-
41 Systems) summarizes the miscellaneous units within the EMF.

4G.3.1 Evaporator Separator Vessel (DEP-EVAP-00001)

1 The evaporator separator vessel (DEP-EVAP-00001) receives feed from the evaporator feed vessel
2 (DEP-VSL-00002) and circulates the contents through the evaporator reboiler (DEP-RBLR-00001). The
3 stream from the evaporator reboiler is introduced below the liquid level and flashes to steam in the vacuum
4 atmosphere at the liquid surface. The overhead vapors, consisting mainly of water, are processed to
5 remove entrained liquid, with the overhead vapor continuing on to the evaporator primary condenser
6 (DEP-COND-00001). The majority of the bottom liquid is recycled through the evaporator reboiler with a
7 small amount sent to the evaporator concentrate vessels (DEP-VSL-00003A/B/C).

8 The evaporator separator vessel is equipped with nozzles in the vessel to spray process condensate on the
9 demister pads and with an impingement plate tray to remove larger water droplets. The evaporator
10 separator vessel also has a nozzle for injection of antifoam reagent. A circulation pump is used to transfer
11 evaporator separator vessel contents to the evaporator reboiler. The evaporator reboiler adds heat to the
12 contents to cause evaporation in the evaporator separator. Multiple transfer options are considered
13 depending on the density, flow, and radiation of the concentrate; the effluent may be discharged to the
14 evaporator concentrate vessels, recirculated back to the evaporator separator vessel, or if off-specification,
15 transferred to the evaporator feed vessel. In addition, a drain line is provided from the evaporator
16 separator vessel to the low-point drain vessel (DEP-VSL-00001) to drain the evaporator during
17 maintenance.

4G.3.2 Evaporator Primary Condenser (DEP-COND-00001)

18 The evaporator primary condenser (DEP-COND-00001) is the primary condenser for the evaporator
19 separator vessel (DEP-EVAP-00001). The overhead vapors from the top of the evaporator separator vessel
20 are condensed in the shell and tube condenser using a secondary cooling water loop. The condensate is
21 pumped to the overhead sampling vessels (DEP-VSL-00004A/B) by evaporator condensate pumps
22 (DEP-PMP-00006A/B), or sent back to the evaporator separator vessel as reflux. A portion of the
23 condensate is also filtered via the condensate duplex cartridge filters (DEP-FILT-00004A/B) and used to
24 spray the demister pads and for intermittent wash down of the evaporator separator vessel.

25 The vacuum for the evaporator separator vessel is established and maintained through condensing the
26 vapor into liquid in the evaporator primary condenser. The first stage ejector (DEP-EJCTR-00001) is used
27 for additional pressure control in the evaporator separator vessel.

4G.3.3 Evaporator Inter-Condenser (DEP-COND-00002)

28 Non-condensable overhead vapor is moved from the evaporator separator vessel (DEP-EVAP-00001) and
29 evaporator primary condenser (DEP-COND-00001) via the first stage ejector and discharged to the
30 evaporator inter-condenser (DEP-COND-00002). The evaporator inter-condenser and evaporator after-
31 condenser (DEP-COND-00003) work with the steam ejectors to create a vacuum in the evaporator
32 separator vessel.

4G.3.4 Evaporator After-Condenser (DEP-COND-00003)

33 The second stage ejector (DEP-EJCTR-00002) pulls vapor from evaporator inter-condenser (DEP-COND-
34 00002) and discharges into the evaporator after-condenser (DEP-COND-00003), where the steam is
35 condensed and the remaining vapor is drawn into the vessel vent header. The condensate from the
36 condensers flows to a drain pot on the boot of the primary condenser, from there it is pumped by
37 evaporator condensate pumps (DEP-PMP-00006A/B) to the overhead sampling vessels (DEP-VSL-
38 00004A/B), and/or back to the evaporator separator vessel (DEP-EVAP-00001) to be used as continuous
39 mesh-wash spray or intermittent wash-down, or sent back to the evaporator feed vessel as reflux.

4G.3.5 Process Condensate Filter (DEP-FILT-00002)

1 Prior to transfer to LERF/ETF, effluent is filtered through a 5-micron process condensate filter
2 (DEP-FILT-00002) downstream of the process condensate lag storage transfer pumps (DEP-PMP-
3 00005A/B).

4G.3.6 Evaporator Feed Prefilter (DEP-FILT-00003)

4 The evaporator feed prefilter (DEP-FILT-00003) is used to remove solids larger than 5 microns from the
5 effluent entering the evaporator feed vessel (DEP-VSL-00002). It filters all effluent except for off-
6 specification recycled condensate from overhead sampling vessels (DEP-VSL-00004A/B), contaminated
7 secondary condensate from reboiler condensate collection vessel (DEP-VSL-00008), and off-specification
8 concentrate from evaporator separator vessel (DEP-EVAP-00001). Filtered solids are flushed to the
9 evaporator concentrate vessels (DEP-VSL-00003A/B/C), where the solids are mixed with the evaporator
10 concentrate for transfer back to the LAW Vitrification Facility or filtered through the evaporator feed
11 prefilter and sent the Hanford Tank Farms. Filtered solids do not enter the evaporator feed vessel.

4G.3.7 Condensate Duplex Cartridge Filters (DEP-FILT-00004A/B)

12 A portion of the condensate from the evaporator primary condenser (DEP-COND-00001) is also filtered
13 via the condensate duplex cartridge filters (DEP-FILT-00004A/B) and used to spray off the demister pads
14 or for intermittent wash down of the evaporator separator vessel (DEP-EVAP-00001).

4G.3.8 Evaporator Concentrate/Feed Vessels LAW Effluent Cooler (DEP-HX-00001)

15 The evaporator concentrate/feed vessels LAW effluent cooler (DEP-HX-00001) uses plant cooling water
16 to cool the effluent stream prior to return to Hanford Tank Farms per the Tank Farm acceptance criteria; it
17 is a plate and frame heat exchanger, where metal plates are used to transfer heat between the effluent and
18 the plant cooling water. The effluent stream may be mixed with sodium nitrite and/or process condensate,
19 as necessary.

4G.3.9 Evaporator Reboiler (DEP-RBLR-00001)

20 The evaporator reboiler (DEP-RBLR-00001) is a forced flow shell and tube reboiler that heats the high
21 flow rate bottom stream from the evaporator separator vessel (DEP-EVAP-00001). The process fluid is on
22 the tube side, with saturated steam on the shell side. The evaporator circulation pump (DEP-PMP-00017)
23 is used to circulate evaporator separator vessel contents through the evaporator reboiler and back to the
24 evaporator separator vessel. The heat input from the stream is adjusted depending on the temperature,
25 level, and vaporization rate in the evaporator separator vessel. The evaporator reboiler has temperature and
26 level sensing capabilities on the utility outlet piping, which interfaces with the Process Control System
27 (PCJ) to remotely monitor temperature and level on the process fluid side. Also, the evaporator reboiler
28 has conductivity sensing capability for the utility side of the reboiler, which interfaces with the PCJ to
29 remotely monitor the evaporator reboiler for tube leaks. The reboiler condensate collection vessel (DEP-
30 VSL-00008) manages clean steam condensate as part of a closed loop system. During normal operations,
31 it does not handle dangerous waste or mixed waste.

4G.4 SECONDARY CONTAINMENT AND RELEASE DETECTION FOR EMF

32 The EMF is constructed of steel reinforced concrete. The design ensures that the containment units have
33 sufficient structural strength to prevent collapse or failure. The primary barriers of the EMF containment
34 units are designed to withstand loads from the movement of personnel, wastes, and equipment handling.
35 Stainless steel liners are provided on the interior floors, and a portion of the walls, for the areas containing
36 the low-point drain vessel (DEP-VSL-00001), the evaporator feed vessel (DEP-VSL-00002), and the
37 evaporator concentrate vessels (DEP-VSL-00003A/B/C). The remaining containment areas are provided
38 with special protective coatings that are constructed with chemical-resistant water stops and compatible
39 with the stored waste.

1 The specifications for the preparation, design, and construction of the secondary containment systems are
2 documented in Operating Unit Group 10, Appendix 13.7, and designed to applicable national codes and
3 standards. Construction of tank systems to required specifications ensures that foundations are capable of
4 supporting tank and secondary containment systems and that uneven settling and failures from pressure
5 gradients will not occur.

6 [Table 4G-3](#), Effluent Management Facility Secondary Containment Rooms/Areas and [Table 4G-4](#),
7 Effluent Management Facility Sumps, Leak Detection Boxes (LDB), Drain Lines and Floor Drains,
8 summarizes the EMF secondary containment systems.

4G.4.1 Low-Point Drain Sump (DEP-SUMP-00001)

9 The low-point drain sump (DEP-SUMP-00001) is used to capture overflow effluent from the low-point
10 drain vessel (DEP-VSL-00001). In addition, underground waste transfer line leak detection box drain
11 headers discharge to the low-point drain sump. The low-point drain sump discharges to the evaporator
12 feed vessel (DEP-VSL-00002). The liquid level in the low-point drain sump is monitored with
13 transmitters that communicate with the PCJ and provide control room alarm indication.

4G.4.2 Pipeline Containment and Leak Detection

14 The DEP System has LDBs on the headers of the coaxial underground waste transfer piping. Leak
15 detection boxes are provided for the underground transfer lines from LAWPS to LAW Vitrification
16 Facility. Leak detection boxes are also provided on underground transfer lines between EMF and LAW
17 Vitrification Facility, between EMF and Lab, between EMF and the Hanford Tank Farms, and between
18 EMF and the LERF/ ETF. The WTP underground transfer line LDBs are located in the LAW effluent
19 drain tank building (Room ED-B001) with the exception of the LERF/ ETF transfer line LDBs which are
20 located at the interface point on the WTP property line. The LDBs are designed to detect a leak within
21 the annular space of the coaxial piping. The liquid level in the sumps is monitored with transmitters that
22 communicate with the PCJ and provide control room alarm indication.

23 Within EMF, the pipelines associated with the tank systems/miscellaneous units are primarily
24 single-walled. Secondary containment is provided for piping within the plant through the use of special
25 protective coatings and waterstops or stainless liners in process areas and process rooms. A short section
26 of process piping is located in a pipe chase in Room ED-CH01, between the west process area and the
27 low-point drain tank area, where coaxial piping is used. The leak detection equipment located within the
28 process areas and process rooms sumps alert operators of a piping leak through the use of level detection
29 instrument alarms. The west process area and the low-point drain area are connected by a pipe chase with
30 coaxial piping that drains to the low-point drain sump (DEP-SUMP-00001).

31 For all secondary containment area sumps, residual liquids may be present after the sump has been
32 flushed and pumped using the large transfer pump. When residual liquid is detected in sumps in readily
33 accessible areas, an entry will occur to remove the residual liquid using a portable sump pump or
34 absorbent device. An exception to this process is in place for the feed vessel area sumps (DEP-SUMP-
35 00004A/B) in room E-0105. These sumps include designated sample pumps (DEP-PMP-00042A/B)
36 located in the EMF Sampling Fume Hood (DEP-HOOD-00001). The pumps are designed to support
37 sampling of the sumps as well as the removal of small volumes of precipitation or residual liquids after
38 the large transfer pump has completed the transfer.

39 The leak detection instrumentation for all secondary containment area sumps include a Level
40 Computation Relay (LKY) function. The LKY function indicates an increase in fluid levels in the sump,
41 even when residual liquid is present.

42 Design details for EMF Sumps, LDBs, drain lines and floor drains are included in [Table 4G-4](#), and are
43 shown on the process and instrumentation diagrams for DEP systems located in Operating Unit Group 10,
44 Appendix 13.2.

4G.4.3 Evaporator Secondary Containment System

1 The secondary containment system and associated ancillary equipment for the evaporator separator vessel
2 (DEP-EVAP-00001) is located in the area known as the west process area, located in the LAW effluent
3 process building. The west process area sumps (DEP-SUMP-00002A/B) are located in Room E-0103.
4 The west process area sumps and level detection instruments detect leakage from the evaporator separator
5 vessel, evaporator feed prefilter (DEP-FILT-00003), and the additional ancillary equipment associated
6 with the evaporator separator vessel. The west process area is sloped to the room sumps and is provided
7 with a special protective coating and waterstops as part of secondary containment.

8 Fluid contained in the west process area sumps is transferred to the overhead sampling vessels
9 (DEP-VSL-00004A/B) or the low-point drain vessel (DEP-VSL-00001) by sump pumps (DEP-PMP-
10 00032A/B). The liquid level in the west process area sumps is monitored with transmitters that
11 communicate with the PCJ and provide control room alarm indication.

4G.4.4 Evaporator Condenser Secondary Containment System

12 The secondary containment system for the evaporator condensers (DEP-COND-00001/2/3) and associated
13 ancillary equipment is located in the area known as the east process area. The east process area sumps
14 (DEP-SUMP-00003A/B) are located in Room E-0102. The east process area sumps and level detection
15 instruments detect leakage from the evaporator condensers, the evaporator reboiler (DEP-RBLR-00001),
16 the evaporator concentrate/feed vessels LAW effluent cooler (DEP-HX-00001), and the ancillary
17 equipment associated with the evaporator condensers and evaporator reboiler. The east process area is
18 sloped to the east process area sumps and is provided with a special protective coating and waterstops as
19 part of secondary containment.

20 Fluid contained in the east process area sumps is transferred to the process condensate lag storage vessels
21 (DEP-VSL-00005A/B) by sump pumps (DEP-PMP-00033A/B). The liquid level in sumps is monitored
22 with transmitters that communicate with the PCJ and provide control room alarm indication.

4G.4.5 Process Condensate Vessel Area Sumps (DEP-SUMP-00005A/B)

23 The process condensate vessel area sumps (DEP-SUMP-00005A/B) are located in Room E-0106. The
24 process condensate vessel area sumps are equipped with level detection instruments to detect precipitation
25 or leakage from the overhead sampling vessels (DEP-VSL-00004A/B) and the process condensate lag
26 storage vessels (DEP-VSL-00005A/B). The process condensate vessel area sumps also collect leakage
27 from ancillary equipment located in this room. Room E-0106 is sloped to the sumps and is provided with
28 a special protective coating and waterstops as part of secondary containment.

29 Fluid contained in the process condensate vessel area sumps is transferred to the process condensate lag
30 storage vessels (DEP-VSL-00005A/B) by sump pumps (DEP-PMP-00035A/B). Room E-0106 is an easily
31 accessible area, and sump liquid will be transferred to the lag storage vessels after an operator verifies that
32 the source of the sump effluent did not originate in either of the lag storage vessels. When effluent is
33 transferred from a sump to a vessel in a shared secondary containment area, the effluent will only be
34 transferred to a non-leaking vessel.

35 If sampling verifies that the source of liquid in the overhead sampling vessel area sumps is precipitation,
36 large volumes of precipitation can be transferred to the process condensate lag storage vessels (DEP-VSL-
37 00005A/B) to be treated and disposed at the LERF/ETF. If small volumes of precipitation are
38 accumulated, the liquid from the sumps can be manually transferred to a container and managed as non-
39 dangerous waste. The effluent in the sumps will be removed within 24 hours or as practicable after receipt
40 of the sample results.

41 A small volume of residual liquids may be present after the sump has been flushed and pumped using the
42 large transfer pump. When residual liquid is detected in Room E-106 sumps, an entry will occur to
43 remove the residual liquid using a portable pump or absorbent spill devices.

1 The liquid level in the sump is monitored and the sump is equipped with level transmitters that
2 communicate with the PCJ and provide a control room alarm indication. The leak detection
3 instrumentation for all secondary containment area sumps include a LKY function. The LKY function
4 indicates an increase in fluid levels in the sump, even when residual liquid is present.

4G.4.6 Feed Vessel Area Sumps (DEP-SUMP-00004A/B)

5 The feed vessel area sumps (DEP-SUMP-00004A/B) are located in Room E-0105 and provide leak
6 detection for the evaporator feed vessel (DEP-VSL-00002) and the evaporator concentrate vessels (DEP-
7 VSL-00003A/B/C). The sumps also collect leakage from ancillary equipment or precipitation collected in
8 Room E-0105. The room is sloped to the feed vessel area sumps. The secondary containment area
9 located in the room is provided with a stainless steel liner. The liquid level in the feed vessel area sumps
10 is monitored with transmitters that communicate with the process control system (PCJ) and provide
11 control room alarm indication. Due to radiation dose rates there is limited access to Room E-0105.

12 If sampling verifies that source of liquid in the feed vessel area sumps is precipitation, large volumes of
13 precipitation can be transferred to the overhead sampling vessels to be returned to the process. If small
14 volumes of precipitation are accumulated, the liquid from the sample pumps (DEP-PMP-00042A/B) will
15 be discharged to the DEP-HOOD-00001 drain that discharges to the low-point drain vessel (DEP-VSL-
16 00001). Alternately, precipitation can be discharged to a container and managed as non-dangerous waste.
17 The effluent in the sumps will be removed within 24 hours or as practicable after receipt of the sample
18 results.

19 A small volume of residual liquids may be present after the sump has been flushed and pumped using the
20 large transfer pump. When residual liquid is detected the sample pumps (DEP-PMP-00042A/B) can be
21 used to remove the residual liquids after the large transfer pump has completed the transfer.

22 The leak detection instrumentation for all secondary containment area sumps include a LKY function.
23 The LKY function indicates an increase in fluid levels in the sump, even when residual liquid is present.
24 The feed vessel area sumps are equipped with pumps that transfer the liquid to the appropriate vessel; the
25 liquid is transferred after sampling occurs to characterize the liquid. Precipitation collected in the feed
26 vessel area sumps can be transferred by sump pumps (DEP-PMP-00034A/B) to the overhead sampling
27 vessels (DEP-VSL-00004A/B). Effluent from a spill is transferred to the low-point drain vessel (DEP-
28 VSL-00001) by sump pumps (DEP-PMP-00034A/B) and recycled back into the process.

4G.5 AIR EMISSION CONTROL

4G.5.1 Direct Feed LAW EMF Vessel Vent Process System (DVP)

29 The Direct Feed LAW EMF Vessel Vent Process System (DVP) is comprised of two main parts, air intake
30 and exhaust. The DVP is designed to maintain hydrogen levels below dangerous levels and remove mixed
31 waste particulates that may be present in the gases that fill the headspace of select DEP System process
32 vessels. The DEP System process vessels and condenser that directly interface with the DVP are the low-
33 point drain vessel (DEP-VSL-00001), evaporator feed vessel (DEP-VSL-00002), evaporator concentrate
34 vessels (DEP-VSL-00003A/B/C), overhead sampling vessels (DEP-VSL-00004A/B), process condensate
35 lag storage vessels (DEP-VSL-00005A/B) and the evaporator after condenser (DEP-COND-00003). The
36 headspace in the evaporator separator vessel (DEP-EVAP-00001) is exhausted by the DVP through the
37 evaporator condensers (DEP-COND-00001/2/3). The inlet air is taken from lower contamination areas
38 throughout the building to provide purged air for maintaining the DEP System process vessels below the
39 lower flammability limit for hydrogen.

40 In the LAW effluent process building, the exhaust air is sent through a preheater (DVP-HTR-00001A/B),
41 two-stages of HEPA filters (DVP-HEPA-00004A/B) and (DVP-HEPA-00003A/B), and an exhaust fan
42 (DVP-EXHR-00001A/B). The exhaust fan is downstream of the DEP System process vessels, preheater
43 and HEPA filters, to ensure that the DEP System vessel headspaces are at negative pressure.

1 Downstream of the EMF Active Confinement Ventilation System (ACV) HEPA filters and exhaust fans,
2 the treated DVP offgas ties into the LAW effluent utility building exhaust duct, where it is discharged
3 through the 150-foot-high EMF stack. The tie-in point to the LAW effluent utility building exhaust duct is
4 upstream of the stack monitoring systems, which monitor the exhaust air streams prior to discharge to the
5 atmosphere.

4G.6 EMF PROCESS SAMPLING

6 A liquid sampling station (DEP-HOOD-00001) is provided for the manual sampling of eight unique EMF
7 process fluid streams, while maintaining the safety of the operator/worker. The sampling station consists
8 of a standard fume hood, the low-point drain vessel (DEP-VSL-00001) process pipelines, manual
9 sampling collection points, utilities systems and a drain system. The seven EMF process sample streams
10 include samples from:

- 11 • DEP-VSL-00001
- 12 • DEP-VSL-00002
- 13 • DEP-VSL-00003A/B/C
- 14 • DEP-VSL-00004 A/B
- 15 • DEP-VSL-00005A/B
- 16 • DEP-EVAP-00001
- 17 • DEP-HX-00001

18 The fume hood functions to capture, confine, and exhaust fumes, vapors, and particulate matter produced
19 or generated within the enclosure. The process pipelines provide primary containment for the radioactive
20 process fluid to be sampled, and the hood is located within the east process area (Room E-0102).
21 Process pipelines bring the process fluids to the sampling station, recirculate the stream before the
22 sample is collected to ensure the sample is representative for the batch, and provide the means to
23 collect the sample into a sampling bottle. A system of valves is installed on the pipelines and used to
24 control the flow during the sampling. The manual sampling collection points are individual points for
25 each process vessel and are designed to hold and secure the sampling bottle during collection.

26 The utility systems are provided in the sampling station to allow for flushing and cleanup of the
27 sampling lines at completion of the sampling campaign, and cleanup of the sampling station work area,
28 whenever needed. The drain system collects the liquid waste resulting from the line flushing process and
29 from the hood cleanup. The drain system connects the liquid sampling station and drains to the low-point
30 drain vessel (DEP-VSL-00001).

31

1

Table 4G-1 Effluent Management Facility Tank Systems

No.	System	Vessel Number/Location	Description	Material	Approximate Total Volume (US Gallons)	Approximate Dimensions (Inside Diameter × Height or Length in feet) (tangent line/tangent line)
1	DEP	DEP-VSL-00001 ED-B001	Low-point drain vessel	Reserved	18,000	14 ft x 12.75 ft
2	DEP	DEP-VSL-00002 E-0105	Evaporator feed vessel	Reserved	42,300	14 ft x 32 ft
3	DEP	DEP-VSL-00003A E-0105	Evaporator concentrate vessel	Reserved	14,805	12 ft x 13.5 ft
4	DEP	DEP-VSL-00003B E-0105	Evaporator concentrate vessel	Reserved	14,805	12 ft x 13.5 ft
5	DEP	DEP-VSL-00003C E-0105	Evaporator concentrate vessel	Reserved	14,805	12 ft x 13.5 ft
6	DEP	DEP-VSL-00004A E-0106	Overhead sampling vessel	Reserved	40,800	14 ft x 30.75 ft
7	DEP	DEP-VSL-00004B E-0106	Overhead sampling vessel	Reserved	40,800	14 ft x 30.75 ft
8	DEP	DEP-VSL-00005A E-0106	Process condensate lag storage vessel	Reserved	127,260	25 ft x 29.5 ft
9	DEP	DEP-VSL-00005B E-0106	Process condensate lag storage vessel	Reserved	127,260	25 ft x 29.5 ft

1
2**Table 4G-2 Effluent Management Facility Miscellaneous Units (Systems and Sub-Systems)**

No.	System/ Subsystem	Component Number/Location	Description	Material	Total Volume (US gallons)
Effluent Management Facility					
1	DEP	DEP-COND-00001 E-0102	DEP Evaporator Primary Condenser	Reserved	NA
2	DEP	DEP-COND-00002 E-0102	DEP Evaporator Inter-Condenser	Reserved	NA
3	DEP	DEP-COND-00003 E-0102	DEP Evaporator After-Condenser	Reserved	NA
4	DEP	DEP-EVAP-00001 E-0103	DEP Evaporator Separator Vessel	Reserved	NA
5	DEP	DEP-FILT-00002 E-0103	DEP Process Condensate Filter	Reserved	NA
6	DEP	DEP-FILT-00003 E-0103	DEP Evaporator Feed Prefilter	Reserved	NA
7	DEP	DEP-FILT-00004A E-0102	DEP Condensate Duplex Cartridge Filter	Reserved	NA
8	DEP	DEP-FILT-00004B E-0102	DEP Condensate Duplex Cartridge Filter	Reserved	NA
9	DVP	DVP-HTR-00001A E-0102	Process Ventilation Preheater	Reserved	NA
10	DVP	DVP-HTR-00001B E-0102	Process Ventilation Preheater	Reserved	NA
11	DVP	DVP-HEPA-00003A E-0102A	Process Ventilation Primary HEPA Filter	Reserved	NA
12	DVP	DVP-HEPA-00003B E-0102A	Process Ventilation Primary HEPA Filters	Reserved	NA
13	DVP	DVP-HEPA-00004A E-0102A	Process Ventilation Secondary HEPA Filters	Reserved	NA
14	DVP	DVP-HEPA-00004B E-0102A	Process Ventilation Secondary HEPA Filters	Reserved	NA
15	DEP	DEP-HX-00001 E-0103	Evaporator Concentrate/Feed Vessels LAW Effluent Cooler	Reserved	NA

No.	System/ Subsystem	Component Number/Location	Description	Material	Total Volume (US gallons)
16	DEP	DEP-RBLR-00001 E-0103	DEP Evaporator Reboiler	Reserved	NA
17	DVP	DVP-EXHR-00001A E-0102	Process Ventilation Exhausters	Reserved	NA
18	DVP	DVP-EXHR-00001B E-0102	Process Ventilation Exhausters	Reserved	NA

1 **Table 4G-3 Effluent Management Facility Secondary Containment Rooms/Areas**

Room/Area	Approximate Room/Area Dimensions (L×W, in feet)	Miscellaneous Treatment Units or Tanks in Room/Area (Largest Plant Item)	Volume of Largest Plant Item in Room/Area (US Gallons)	Minimum Secondary Containment Height (feet)
E-0102 east evaporator process area	62 ft x 94 ft 6 in.	Process condensate lag storage vessel	127,260	4 ft 6 in.
E-0103 west evaporator process area	62 ft x 56 ft 6 in.	Evaporator feed vessel	42,300	3 ft 5 in.
ED-B001 low-point drain vessel area	28 ft x 33 ft	Low-point drain vessel	18,000	4 ft 2 in.
E-0105-evaporator feed vessel area	45 ft 6 in. x 39 ft	Evaporator feed vessel	42,300	5 ft 2 in.
E-0106 process condensate lag storage vessel area	45 ft 6 in. x 84 ft 4 in.	Process condensate lag storage vessel	127,260	6 ft 10 in.

1
2**Table 4G-4 Effluent Management Facility Sumps, Leak Detection Boxes, Drain Lines/
Floor Drains**

Sump/Leak Detection Box, or Floor Drain/Line I.D.# and Room#	Maximum Sump/Leak Detection Box Capacity (gallons)	Sump/Leak Detection Box Level Detection Type	Sump, Leak Detection Box or Floor Drain/Line Dimensions (approximate) and Materials of Construction	Piping and Instrumentation Diagram Number
Effluent Management Facility				
Sumps				
DEP-SUMP-00001 ED-B001	~58	Radio Frequency (RF) Capacitance	24 in. Dia. x 30 in. Length 304L SS	24590-BOF -M6-DEP-00001002
DEP-SUMP-00002A E-0103	~58	RF Capacitance	24 in. Dia. x 30 in. Length 304L SS	24590-BOF -M6-DEP-00009001
DEP-SUMP-00002B E-0103	~58	RF Capacitance	24 in. Dia. x 30 in. Length 304L SS	24590-BOF -M6-DEP-00009001
DEP-SUMP-00003A E-0102	~58	RF Capacitance	24 in. Dia. x 30 in. Length 304L SS	24590-BOF -M6-DEP-00009004
DEP-SUMP-00003B E-0102	~58	RF Capacitance	24 in. Dia. x 30 in. Length 304L SS	24590-BOF -M6-DEP-00009004
DEP-SUMP-00004A E-0105	~58	RF Capacitance	24 in. Dia. x 30 in. Length 304L SS	24590-BOF -M6-DEP-00009002
DEP-SUMP-00004B E-0105	~58	RF Capacitance	24 in. Dia. x 30 in. Length 304L SS	24590-BOF -M6-DEP-00009002
DEP-SUMP-00005A E-0106	~58	RF Capacitance	24 in. Dia. x 30 in. Length 304L SS	24590-BOF -M6-DEP-00009005
DEP-SUMP-00005B E-0106	~58	RF Capacitance	24 in. Dia. x 30 in. Length 304L SS	24590-BOF -M6-DEP-00009005
Leak Detection Boxes				
DEP-LDB-00001 ED-B001	~7	Conductivity Switch	8 in. Dia. x 41 in. Length 316L SS	24590-BOF -M6-DEP-00011001
DEP-LDB-00002			8 in. Dia. x 41 in. Length	24590-BOF

ED-B001	~7	Conductivity Switch	316L SS		-M6-DEP-00011001
DEP-LDB-00003 ED-B001	~7	Conductivity Switch	8 in. Dia. x 41 in. Length 316L SS		24590-BOF -M6-DEP-00011001
DEP-LDB-00004 ED-B001	~7	Conductivity Switch	8 in. Dia. x 41 in. Length 316L SS		24590-BOF -M6-DEP-00011001
DEP-LDB-00005 ED-B001	~7	Conductivity Switch	8 in. Dia. x 41 in. Length 316L SS		24590-BOF -M6-DEP-00011001
DEP-LDB-00006 ED-B001	~7	Conductivity Switch	8 in. Dia. x 41 in. Length 316L SS		24590-BOF -M6-DEP-00011001
Drain Lines					
BOF-DEP-ZS-20282-W11A-011/02-01 ED-CH01	NA	NA	4 in. Dia. 316L SS	Containment pipe	24590-BOF -M6-DEP-00001001
			1 ½ in. Dia. AL6XN	Process pipe	
BOF-DEP-ZS-20236-W31A-02-01 ED-CH01	NA	NA	4 in. Dia. Carbon Steel	Containment pipe	24590-BOF -M6-DEP-00001001
			2 in. Dia. 316L SS	Process pipe	
BOF-DEP-ZS-20245 -W11A-04-01ED-CH01	NA	NA	6 in. Dia. 3166 SS	Containment pipe	24590-BOF -M6-DEP-00001001
			4 in. Dia. AL6XN	Process pipe	
BOF-DEP-ZS-20231-W31A-03-01 ED-CH01	NA	NA	6 in. Dia. Carbon Steel	Containment pipe	24590-BOF -M6-DEP-00001001
			3 in. Dia. 316L SS	Process pipe	
BOF-DEP-ZS-20242-W31A-10-01 ED-CH01	NA	NA	14 in. Dia. Carbon Steel	Containment pipe	24590-BOF -M6-DEP-00001001
			10 in. Dia. 316L SS	Process pipe	
BOF-DEP-ZS-20249-W31A-03-01 ED-CH01	NA	NA	6 in. Dia. Carbon Steel	Containment pipe	24590-BOF -M6-DEP-00001001
			3 in. Dia. 316L SS	Process pipe	
BOF-DEP-ZS-20225-W31A-02-01	NA	NA	4 in. Dia. Carbon steel	Containment pipe	24590-BOF

ED-CH01			2 in. Dia. 316L SS	Process pipe	-M6-DEP- 00001002
BOF-DEP-ZS- 20219-W31A-02-01 ED-CH01	NA	NA	4 in. Dia. Carbon steel	Containment pipe	24590-BOF -M6-DEP- 00001002
			2 in. Dia. 316L SS	Process pipe	
BOF-DEP-ZS- 20222-W31A-02-01 ED-CH01	NA	NA	4 in. Dia. Carbon Steel	Containment pipe	24590-BOF -M6-DEP- 00001002
			2 in. Dia 316L SS.	Process pipe	
BOF-DEP-ZS- 20252-W11A-03-01 ED-CH01	NA	NA	6 in. Dia. 316L SS	Containment pipe	24590-BOF -M6-DEP- 00010001
			3 in. Dia. AL6XN	Process pipe	
BOF-DEP-ZS- 20265-W31A-03-01 ED-CH01	NA	NA	6 in. Dia. Carbon Steel	Containment Pipe	24590-BOF -M6-DEP- 00002006
			3 in. Dia. 316L SS	Process pipe	
BOF-DEP-ZY- 00181-W31A-03-01 ED-CH01	NA	NA	6 in. Dia. Carbon Steel	Containment Pipe	24590-BOF -M6-DEP- 00001001
			3 in. Dia. 316L SS	Process pipe	
BOF-DEP-WU- 00008-W31A-03-01 ED-CH01	NA	NA	6 in. Dia. Carbon steel	Containment pipe	24590-BOF -M6-DEP- 00001001
			3 in. Dia. 316L SS	Process pipe	
BOF-DVP-GV- 00026-W31A-03-01 ED-CH01	NA	NA	6 in. Dia. Carbon steel	Containment Pipe	24590-BOF -M6-DEP- 00001001
			3 in. Dia. 316L SS	Process pipe	

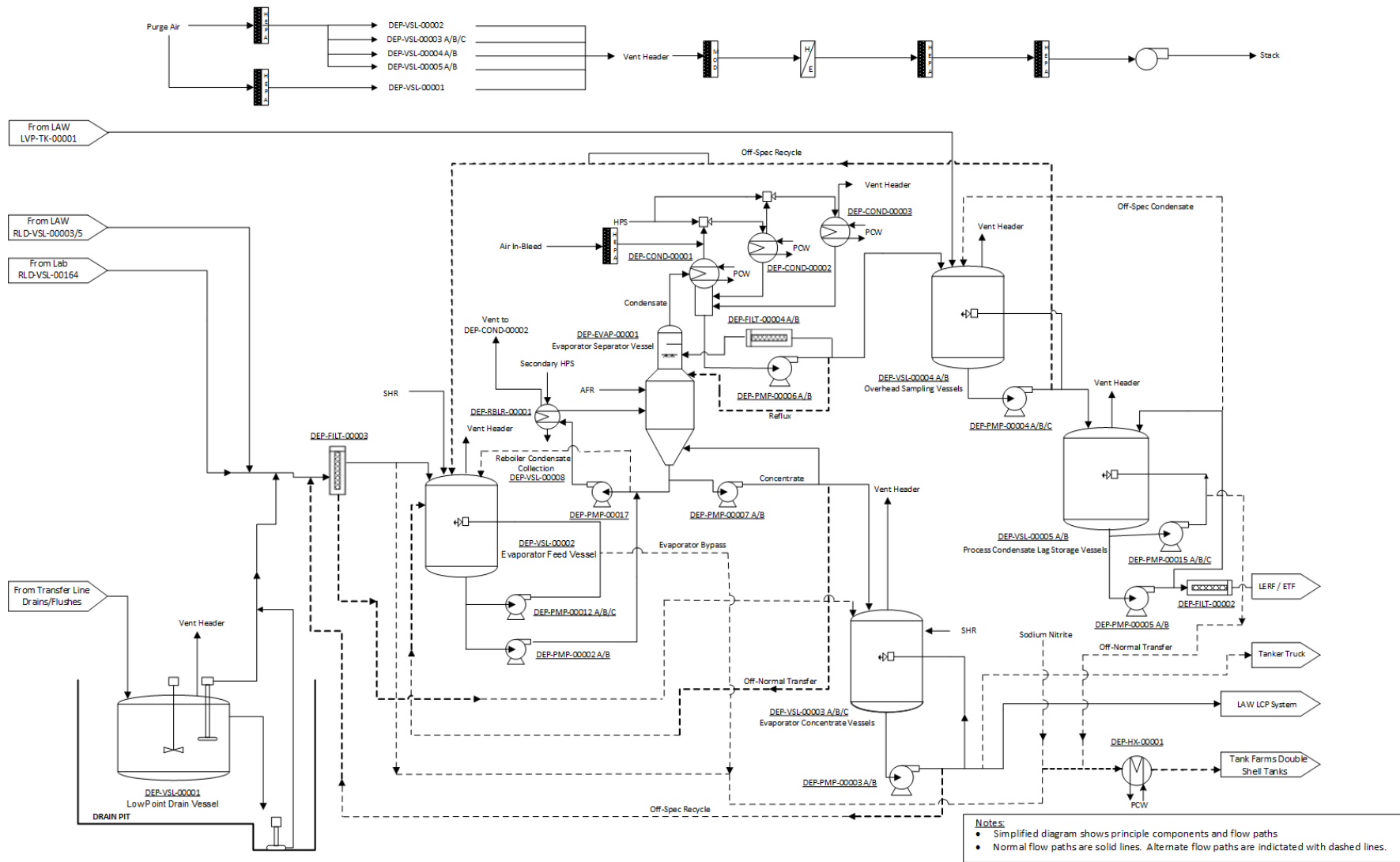


Figure 4G-1 Effluent Management Facility Process Flow

1
2

1
2
3
4
5

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